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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/729,452	12/04/2003	Robert David Allen	ARC920030104US1	2060
23980 7590 04/10/2008 MINTZ, LEVIN, COHN, FERRIS, GLOVSKY AND POPEO, P.C 1400 PAGE MILL ROAD PALO ALTO, CA 94304-1124				
EXAMINER				
CHU, JOHN S Y				
ART UNIT		PAPER NUMBER		
1795				
MAIL DATE		DELIVERY MODE		
04/10/2008		PAPER		

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Office Action Summary

Application No.

10/729,452

Applicant(s)

ALLEN ET AL.

Examiner

JOHN S. CHU

Art Unit

1795

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --
Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 10 January 2008.
2a) ☒ This action is **FINAL**. 2b) ☐ This action is non-final.
3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-15, 19 and 21-35 is/are pending in the application.
4a) Of the above claim(s) _____ is/are withdrawn from consideration.
5) ☐ Claim(s) _____ is/are allowed.
6) ☒ Claim(s) 1-15, 19 and 21-35 is/are rejected.
7) ☐ Claim(s) _____ is/are objected to.
8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
10) ☐ The drawing(s) filed on _____ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
a) ☒ All b) ☐ Some * c) ☐ None of:
1. ☒ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. _____.
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- 1) ☒ Notice of References Cited (PTO-892)
2) ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
3) ☐ Information Disclosure Statement(s) (PTO/SB-08)
Paper No(s)/Mail Date _____
4) ☐ Interview Summary (PTO-413)
Paper No(s)/Mail Date _____
5) ☐ Notice of Informal Patent Application
6) ☐ Other: _____

DETAILED ACTION

This Office action is in response to the amendment filed January 10, 2008.

1. The rejection under 35 U.S.C. 103(a) as being unpatentable over CHOI is **withdrawn** in view of the amendment by applicant.

Claim Rejections - 35 USC § 103

2. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

3. Claims 1-15, 19, and 21-35 are rejected under 35 U.S.C. 103(a) as being unpatentable over CHOI in view of HOULIHAN et al (2004/0265733).

The claimed invention is drawn to the following:

1. **(Currently amended)** A process for patterning a substrate, comprising:

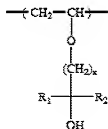
(a) coating the substrate with a film of a photoresist composition comprised of (i) a polymer that is rendered soluble in aqueous base at a temperature of less than about 100°C by acid-catalyzed deprotection of pendent acetal- or ketal-protected carboxylic acid groups, and (ii) a photoacid generator;

(b) patternwise exposing the film to an imaging radiation source so as to form a latent, patterned image in the film;

(c) baking the exposed film at a post-exposure bake temperature below about 100 °C [70°C]; and

(d) developing the latent image with a developer to form a patterned substrate, wherein the polymer is prepared by polymerization of a monomer mixture, the mixture comprising (a) at least one first olefinic monomer containing an acetal or ketal linkage, the acid-catalyzed cleavage of which renders the polymer soluble in aqueous base, and (b) at least one second olefinic monomer selected from (i) an olefinic monomer containing a pendant fluorinated hydroxyalkyl group R^H , (ii) an olefinic monomer containing a pendant fluorinated alkylsulfonamide group R^S , and (iii) combinations thereof.

CHOI discloses a photosensitive polymer and photoresist composition comprising a hydroxyl vinyl ether monomer and a fluorinated alkyl group and a perfluorinated alkyl group monomer, see paragraph [0018] for the following monomer



The R_1 and R_2 are defined as C1 to C20 alkyl groups, C1 to C10 fluorinated alkyl groups or C1 to C10 perfluorinated alkyl groups which meet the recited (i) olefinic monomer containing a fluorinated hydroxyl alkyl group. The recited acetal- or ketal- protected carboxylic group is met

by the side groups disclosed in paragraph [0029], specifically tetrahydropyranyl, or 1-ethoxy ethyl.

The recited method in paragraph [0049] discloses an exposure step to KrF, ArF and F₂ with a post-exposure bake step between 90° C to 180° C. The disclosed range fails to meet the now claimed range of between 25° C and 80° C.

The reference lacks a working example showing a method using a polymer having the acetal- or ketal- group monomer and a hydroxyl alkyl fluorinated monomer wherein the method has a post-exposure bake step of between 25° C and 80° C.

HOULIHAN et al discloses photolithographic method wherein the range for the post-exposure bake step is between 50° C and 80° C, see paragraph [0044] . However the disclosure of the reference lacks a working example showing a method using a polymer having the acetal- or ketal- group monomer and a hydroxyl alkyl fluorinated monomer wherein the method has a post-exposure bake step of between 50° C and 80° C as claimed.

It would have been *prima facie* obvious to one of ordinary skill in the art of pattern formation to use a photoresist compositions comprising a copolymer having monomers with an acetal –or ketal protected carboxylic group as exemplified in paragraph [0029] such as tetrahydropyranyl and 1-ethoxy ethyl groups and a hydroxy alkyl containing fluorinated monomer and have a post-exposure bake step between 50° C and 80° C and reasonably expect same or similar results as recited in CHOI and HOULIHAN et al for excellent transparency at short wavelengths good adhesion, and high resistance to dry etching.

4. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. NISHI et al (2002/0150835) discloses post-exposure bake steps in a range of 50° C and 150° C, see paragraph [0155].

5. Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Examiner Chu whose telephone number is (571) 272-1329. The examiner can normally be reached on Monday - Friday from 9:30 am to 6:00 pm.

If attempts to reach the Examiner by telephone are unsuccessful, the Examiner's supervisor, Cynthia Kelly, can be reached on (571) 272-1526

The fax phone number for the USPTO is (571) 273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PMR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

/John S. Chu/
Primary Examiner, Art Unit 1795

J.Chu
April 4, 2008